# **12. Design Styles**

Bei Yu

**Optional** 

# A System-on-a-Chip: Example



[Courtesy: Philips]

### Implementation Choices



### Impact of Implementation Choices



- Higher custom level, higher energy efficiency
- Higher custom level, lower design efficiency

# The Custom Approach



# The Custom Approach

• Intel 4004



### Transition to Automation and Regular Structures



Intel 4004 ('71)



Intel 8080



Intel 8085



Intel 80286



Intel 80486

[Courtesy: Intel]

## Cell-based Design



## Standard Cell — Example



Path	1.2V - 125°C	1.6V - 40°C			
In $1-t_{pLH}$	0.073+7.98C+0.317T	0.020+2.73 <i>C</i> +0.253 <i>T</i>			
$In1-t_{pHL}$	0.069+8.43C+0.364T	0.018+2.14 <i>C</i> +0.292 <i>T</i>			
$In2-t_{pLH}$	0.101+7.97 <i>C</i> +0.318 <i>T</i>	0.026+2.38 <i>C</i> +0.255 <i>T</i>			
In2—t <sub>pHL</sub>	0.097+8.42 <i>C</i> +0.325 <i>T</i>	0.023+2.14 <i>C</i> +0.269 <i>T</i>			
$In3-t_{pLH}$	0.120+8.00C+0.318T	0.031+2.37 <i>C</i> +0.258 <i>T</i>			
$In3-t_{pHL}$	0.110+8.41C+0.280T	0.027+2.15 <i>C</i> +0.223 <i>T</i>			

3-input NAND cell (ST Microelectronics): C = Local Capacitance T = input rise/fall time

# Cell-based Design

• Standard cells



### Cell-based Design — Example



Routing channel requirements are reduced by presence of more interconnect layers

[Brodersen92]

### Cell-based Design — The New Generation

### Cell-structure hidden under interconnect layers

### Automatic Cell Generation



[Courtesy: Cadabra]

### "Hard" Macro-Modules

- 256×32 (or 8192 bit) SRAM
- Generated by hard-macro module generator

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### "Soft" Macro-Modules

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Synopsys Design Compiler

## Mixed Macro & Standard Cells

#### ISPD98 ibm01



12752 cells, 247 macros

ISPD06 newblue4



#### 642717 cells, 3422 macros

### Array-based Design





- Wafers of pre-diffused transistors are pre-manufactured
- Desired interconnections added to determine the overall function of the chip

# Sea-of-gate Primitive Cells



Using oxide-isolation



Using gate-isolation

### Example: Base Cell of Gate-Isolated GA



### Example: Ocean System



[Courtesy: Ocean in DUT]

- Package link in DUT, the Netherlands.
- Tech report in 1993 by Patrick Groeneveld et al.

# Sea-of-gates

Memory



Random Logic

#### [Courtesy LSI Logic]

# Pre-wired Arrays

Classification of prewired arrays (or field-programmable devices):

### Based on Programming Technique

- Fuse-based (program-once)
- Non-volatile EPROM based
- RAM based

### Programmable Logic Style

- Array-Based
- Look-up Table

### Programmable Interconnect Style

- Channel-routing
- Mesh networks

# Design Methodology



## "Design Closure" Problem



# "Design Closure" Problem





### Iterative Removal of Timing Violations (white lines)

**Courtesy Synopsys** 

### Integrating Synthesis with Physical Design



### Design Challenges — Behavioral Domain



### Multi-Supply Voltage toward Low Power



chip level 1.4 volt: b1,b2,b3 voltage island A (1.3 volt): b4,b5,b6 voltage island B (1.2 volt): b7,b8,b9

Higher level design [Hung+,ICCD'05]



Lower level design [Puri+,ICCAD'05]

### Design Challenges — Structural Domain



#### Challenge:

- Distributed design
- Faster design converge

### Solutions:

- IP re-use
- Network-on-Chips (NoCs)
- etc

# Distributed SoC Design Flow

To overcome design complexity:



**Complexity and Productivity Growth** 

### "Intellectual Property" (IP) Cores



A Protocol Processor for Wireless

# Network-on-Chips (NoCs)



- NoCs: heterogeneous IPs
- Communication through network interface (NI)

### Design Challenges — Physical Domain



Challenge:

Manufacturing

### Solutions:

- Design for Manufacturing
- Advanced lithography
- etc

# Manufacturing Challenges



Near future: multiple patterning lithography for 22nm/14nm ...

Long term future: other advanced lithography

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#### Directly Self-Assembly (DSA)

E-Beam





Courtesy ASML

Extremely Ultra-Violet (EUV)



Triple Patterning Lithography (TPL)